

Atty. Dkt. No. AMAT/6493/ETCH/SILICON/JB

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Nallan, et al.

Serial No.:

09/993,240

Confirmation No.:

6869

Filed: November 13, 2001

For: Apparatus for Controlling a

Thermal Conductivity Profile for a Pedestal in a Semiconductor

Wafer Processing Chamber

MAIL STOP AF

Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

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Group Art Unit:

1763

Examiner:

Ram N. Kackar

CERTIFICATE OF MAILING

37 CFR 1.8

hereby certify that this correspondence is being deposited on , 2004, with the United States Postal Service First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Dear Sir:

RESPONSE TO FINAL OFFICE ACTION DATED NOVEMBER 20, 2003

In response to the Final Office Action dated November 20, 2003, having a shortened statutory period for response set to expire on February 20, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/6493/AOP, \$140.00 for excess claim fees, and any additional amount for other fees, including extension of time fees, required to make this response timely and acceptable to the Office.

Amendments to the claims are reflected in the listing of claims which begins on page 2 of this paper. Remarks begin on page 7 of this paper.

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